



#### NIR-sensitive single-photon devices (SiPM and SPADs in custom technologies), for industrial and automotive LIDAR applications

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September 14-18, 2020









### Outline



- □ Introduction on FBK research topics
- □ Single photon avalanche diodes (SPADs) and Silicon photomultipliers (SiPMs)
  - SiPM characteristics and typical applications
  - FBK SiPM technologies roadmap: "High-density" and "ultra high density" tech.
- Emerging applications for SiPMs
  - NIR spectroscopy and diffuse optics
  - LiDAR (automotive and industrial): requirements, working principle
- □ NIR-sensitivie SiPM technology optimization
  - Issues and requirements
  - Current development and performance
- □ IPCEI at FBK: roadmap and plans for future NIR tech. with 3D integration
  - TSVs on front-illuminated 3D integrated structures
  - Back side illuminated, with charge-drift engineered future NIR SiPM for LiDAR







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Silicon-based detector in full-custom technologies:



4

development for LiDAR



### SPADs and SiPMs





SPAD: Single-Photon Avalanche Diode

(Geiger-mode, single photon counting capabilities). Available in:

- Full-Custom Technology
- CMOS Technology







❑ SiPM: Silicon photomultiplier → thousands of SPADs in parallel

(single detector, single-photon sensitive, but with photon counting capability) Available in:

- Full-Custom Technology
- Digital SiPM d-SiPM (CMOS)



### Silicon Photomultipliers (1)







- Silicon photomultipliers: Thousands of cells in parallel
- But still single-photon sensitive
- High detection efficiency (PDE), up to 50-60%
- Very good time resolution (better than 100ps)
- High linearity and photon-number resolution







### Silicon Photomultipliers (2)





a SiPM is:

**Radiation detector (with** <u>scintillator</u>)

- Medical imaging
- High-energy physics

#### Substitute of PMT (photomultiplier tube)

- Spectroscopy
- Calorimetry

Single-photon detector (with photon number resolution)

- Single-photon spectroscopy
- LiDAR





#### FBK: SiPM tech. roadmap







Fabio Acerbi - NIR SiPMs and SPADs development for LiDAR 8 of 70



### "High-density" technology





- $\Box \quad \text{Trenches between cells} \rightarrow \text{Lower Cross-Talk}$
- □ Cell pitch: 15 50 um
- □ Narrow dead border region  $\rightarrow$  High Fill Factor (>80%)
- □ "simple" fabrication process: 9 lithographic steps





< 3 um





### "Ultra-high-density"





- Reduction of all technological features, including trenches width and contacts.
- □ Circular active area in honeycomb SPAD configuration.
- □ High fill-factor despite the small pitch
  - $\Box$  (down to 5µm, with 40% nominal FF !)







#### SiPM new application: diffuse optical spectroscopy







Source: Re et. al. "Probe-hosted silicon photomultipliers for time-domain functional near-infrared spectroscopy ..."



Source: R. Zimmermann, et. Al. "Silicon photomultipliers for improved detection of low light levels in miniature nearinfrared spectroscopy instruments ..."

- □ Applications: near-infrared spectroscopy / time-domain diffuse optics
- □ SiPMs have been a "revolution" thanks to their
  - Large active area, (large numerical aperture in light collection)
  - But still with single-photon sensitivity, high detection efficiency and good time resolution.







#### SiPM new application: LiDAR







- Requirements: detect up to 200m.
- Detectors requirements:
  - High-sensitivity
  - Good time resolution
  - High dynamic range
  - Small dead-time
- SiPMs are a promising choice
- □ 905÷950 laser → need optimized SiPM technology





- Example: collision protec. on automated vehicles
- □ Requirements:
  - Smaller range
  - But high precision
  - Large field of view
- Reliable and compact system
- SiPMs, APDs, ... are promising choices







#### Automotive LiDAR





![](_page_12_Picture_4.jpeg)

![](_page_12_Picture_6.jpeg)

![](_page_13_Picture_0.jpeg)

## SiPM for Near Infrared (1)

![](_page_13_Picture_2.jpeg)

![](_page_13_Figure_3.jpeg)

![](_page_13_Figure_4.jpeg)

- Red and NIR photons  $\rightarrow$  longer absorption depth in silicon (tens of micrometers)
- Thicker epi-Silicon must be used to increase absorption
- Technology adjustment:
  - thicker trenches (high aspect ratio)
  - Electric field modification to collect deeper in epi-layer

![](_page_13_Figure_10.jpeg)

![](_page_13_Picture_11.jpeg)

![](_page_13_Picture_13.jpeg)

![](_page_14_Picture_0.jpeg)

### SiPM for Near Infrared (2)

![](_page_14_Picture_2.jpeg)

![](_page_14_Figure_3.jpeg)

- □ Issue: the "border effect"
- $\Box$  When increasing epi-layer thickness  $\rightarrow$  more important border effect
- □ Important reduction of effective active area (with respect to nominal AA)
  - It needs a modification of the internal SPAD structure to get high detection efficiency

![](_page_14_Picture_8.jpeg)

![](_page_14_Picture_10.jpeg)

![](_page_15_Picture_0.jpeg)

## SiPM for Near Infrared (3)

![](_page_15_Picture_2.jpeg)

![](_page_15_Figure_3.jpeg)

- □ Applications like LIDAR need:
  - Small cells  $\rightarrow$  fast recharge, to cope with background light
  - but with high PDE
  - Not possible, because of border effect
- New strategies and technological improvements are needed

![](_page_15_Picture_9.jpeg)

![](_page_15_Picture_11.jpeg)

#### Strategies:

Small cells but with improved sensitivity

> Big cells but with reduced CT

Medium cells / small AA - with back reflector - with *micro-lens* (improved sensitivity)

Back-side illuminated cells with charge-drift engineering (improved sensitivity)

![](_page_16_Picture_0.jpeg)

## SiPM for Near Infrared (4)

![](_page_16_Picture_2.jpeg)

1.4E+6

![](_page_16_Figure_3.jpeg)

- NIR-HD tech: current developments status
  - Detection efficiency:  $\sim 12\%$  (25µm SPAD pitch),  $\sim$ 14% (54µm\* SPAD pitch)
  - Dark count rate (DCR): ~800kcps/mm<sup>2</sup>  $\rightarrow$ 500cps per SPAD
  - Crosstalk: ~10% (for both 25µm and 54µm pitch)

![](_page_16_Picture_8.jpeg)

11%

12%

![](_page_16_Picture_10.jpeg)

![](_page_16_Picture_12.jpeg)

5%

13%

14%

15%

![](_page_17_Picture_0.jpeg)

### NIR SiPM array

![](_page_17_Picture_2.jpeg)

![](_page_17_Figure_3.jpeg)

![](_page_17_Figure_4.jpeg)

Over 4000 device tested over the wafer

![](_page_17_Picture_6.jpeg)

- 8÷16 elements.
- Small cell pitch (25µm) for reducing saturation issues.
- Fast single-SPAD recharge time.
- Good uniformity in performance is needed (e.g. noise and efficiency)

Breakdown voltage: typ.  $\pm 0.15$ 

![](_page_17_Picture_12.jpeg)

![](_page_17_Picture_14.jpeg)

![](_page_18_Picture_0.jpeg)

#### FBK IPCEI Roadmap for 3D-integrated SPADs & SiPMs

![](_page_18_Picture_2.jpeg)

![](_page_18_Figure_3.jpeg)

- □ 3D integrated SPADs and SiPMs:
  - better sensitivity
  - more functionality per pixel
  - each tier can be independently optimized using dedicated processes

![](_page_18_Picture_8.jpeg)

![](_page_18_Picture_10.jpeg)

![](_page_19_Picture_0.jpeg)

## 3D Integration at FBK

![](_page_19_Picture_2.jpeg)

Front Side Illumination with TSVs: for NUV/VUV-sensitive detector

![](_page_19_Figure_4.jpeg)

#### Back Side Illumination: for NIR-sensitive detector

![](_page_19_Figure_6.jpeg)

![](_page_19_Picture_7.jpeg)

![](_page_20_Picture_0.jpeg)

### 3D Integration at FBK

![](_page_20_Picture_2.jpeg)

- Example of Back Side illumination for Visible/NIR SiPMs
  - Wafer bonding
  - Wafer thinning (down to epi layer)
  - Surface passivation (new ARC)

![](_page_20_Figure_7.jpeg)

![](_page_20_Figure_8.jpeg)

■ Metal reflector can be used → increasing the effective absorption length of NIR photons.

![](_page_20_Figure_10.jpeg)

![](_page_20_Figure_11.jpeg)

![](_page_20_Picture_12.jpeg)

![](_page_20_Picture_14.jpeg)

![](_page_21_Picture_0.jpeg)

# Future NIR-HD tech. developments: charge-drift engineered SPADs

![](_page_21_Picture_2.jpeg)

![](_page_21_Figure_3.jpeg)

- □ Back side illuminated
  - With metal mirror → double effective absorption length.

#### □ With microlens

- Shaping light spot inside active volume
- □ Charge-drift paths engineering
  - Small active area, but with big collection volume!
- Bump bonding to read-out chip or discrete electronics

![](_page_21_Picture_11.jpeg)

![](_page_21_Picture_13.jpeg)

![](_page_22_Picture_0.jpeg)

![](_page_22_Picture_1.jpeg)

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Thank you

![](_page_22_Picture_5.jpeg)

![](_page_22_Picture_6.jpeg)

![](_page_22_Picture_7.jpeg)